Approval of the thesis:

REDUCTION OF SILICON DIOXIDE BY ELECTROCHEMICAL DEOXIDATION

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Signature:
Electrochemical reductions of porous SiO₂ pellets and bulk SiO₂ plate were investigated in molten CaCl₂ and/or CaCl₂-NaCl salt mixture. The study focused on effects of temperature, particle size of the starting material, electrolyte composition and cathode design on the reduction rate. The behavior of the cathode contacting materials was also examined. Moreover, cyclic voltammetry study was conducted to investigate the mechanism of the electrochemical reaction. Mainly, XRD analysis and SEM examinations were used for characterizations.

The rates of electrochemical reduction were interpreted from the variations of current and accumulative electrical charge that passed through the cell as a function of time under different conditions. The results showed that reduction rate of SiO₂ increased slightly with increasing temperature or decreasing the particle size of SiO₂ powder. Higher reduction rate was obtained when porous pellet was replaced by bulk SiO₂ plate. Use of Kanthal wire mesh around the SiO₂ cathode increased but addition of NaCl to the electrolyte decreased the reduction rate.
X-ray diffraction results confirmed the reduction of SiO$_2$ to Si in both CaCl$_2$ salt and CaCl$_2$-NaCl salt mixture. However, silicon produced at the cathode was contaminated by the nickel and stainless steel plates which were used as the cathode contacting materials. Microstructures and compositions of the reduced pellets were used to infer that electrochemical reduction of SiO$_2$ in molten salts may become a method to produce solar grade silicon (SOG-Si).

In addition, overall reduction potential of SiO$_2$ pellet against the graphite anode and the potential of the cathode reaction at 750°C in molten CaCl$_2$-NaCl salt mixture were determined as 2.3 V (at 1.19 A current) and 0.47 V, respectively by cyclic voltammetry.

**Keywords:** Silicon, Silicon Dioxide, Electrodeoxidation, Molten Salt
ÖZ

SİLİYSUM DİOKSİTİN ELEKTROKİMYASAL DEOKSİDASYON YÖNTEMİYLE İNDİRGENMESİ

Ergül, Emre

Yüksek Lisans, Metalurji ve Malzeme Mühendisliği Bölümü
Tez Yöneticisi: Prof. Dr. Ishak Karakaya

Temmuz 2010, 67 sayfa


Elektrokimyasal indirgenmenin hızı, farklı koşullar altında elektroliz hücresinden geçen akımın ve toplam yükün zamana göre değişimlerinden yorumlanmıştır. Elde edilen sonuçlar, SiO₂’in indirgenme hızının sıcaklığın artırılmasıyla veya tane boyutunun küçültülmesiyle az miktarda da olsa arttığını göstermiştir. SiO₂ pelet yerine SiO₂ plaka kullanıldığında daha yüksek indirgenme hızı elde edilmiştir. Bunların yanında, SiO₂’in kantal tel örgü ile sarılması indirgenme hızını artırdığı, elektrolitin içersine NaCl eklenmesi indirgenme hızını düşürmüştür.
X-ışınları analiz sonucu SiO$_2$'in hem CaCl$_2$ tuzu içerisinde hem de CaCl$_2$-NaCl tuz karışım içerisinde silisyuma indirgendiğini göstermiştir. Fakat, iletken malzeme olarak kullanılan nikel ve çelik plakalar, katotta üretilen silisyumu kirletmiştir. İndirgenen peletlerin mikro yapı ve kompozisyon analizleri, SiO$_2$'ın erimiş tuz içerisinde indirgenmesinin güneşten enerji üretmekte kullanılabilecek kalitede silisyum üretilmesi için bir metot olabilmesine yönelik çıkarımlar yapmak için kullanılmıştır.

Bunlara ek olarak, SiO$_2$ peletin grafit anota karşı (1,19 A akımda) toplam indirgenme ve katot elektrot potansiyelleri, döngülü voltametri çalışmasıyla 750°C'de erimiş CaCl$_2$-NaCl tuz çözeltisi içerisinde, 2,3 V ve 0,47 V olarak ölçülmüştür.

**Anahtar Kelimeler:** Silisyum, Silisyum Dioksit, Elektrodeoksidasyon, Erimiş Tuz
To My Family & Pelin...
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CHAPTER 1

INTRODUCTION

1.1 Properties of Silicon

Silicon, Si, is a nonmetallic, gray, semiconducting element with atomic number 14 and mass 28.086. Silicon is one of the most abundant elements in the earth and it exists as oxides and silicates. Also it is very important semiconducting material due to its atomic structure. Doping with a group IIIA element like boron, one silicon atom substituted with this element in the crystal structure, but it provides one less valance electron than silicon. Therefore one valence electron of silicon can shift to that hole. Due to that shifting, extrinsic conduction becomes possible. Semiconductors with this type of doping are referred to as p-type semiconductors. If silicon atom substituted with a group VA element, there is one extra electron in the bonding. Semiconductors with this type of doping are referred to as n-type semiconductors. Therefore it is possible to decrease electrical resistivity by doping silicon with electrically active elements, for instance B, Al or P. In addition, electrical resistivity of silicon decreases with increasing temperature. Some physical properties of silicon are given in Table 1.1 [1].

As a semiconductor, silicon is most widely used one among other semiconductors, due to its unique advantages. It is easy to control the composition of elemental silicon and its conduction properties. A large variety of impurity atoms can be used to modify the composition and conduction properties of silicon. In addition, silicon can be used at relatively high temperatures without losing its conduction characteristics.
Table 1.1: Some physical properties of silicon [1]

<table>
<thead>
<tr>
<th>Property</th>
<th>Value</th>
</tr>
</thead>
<tbody>
<tr>
<td>Atomic number:</td>
<td>14</td>
</tr>
<tr>
<td>Atomic mass</td>
<td>28.086</td>
</tr>
<tr>
<td>Lattice constant:</td>
<td>0.5431 nm (=edge length of the cubic unit cell)</td>
</tr>
<tr>
<td>Interatomic distance in &lt;111&gt; direction</td>
<td>0.2352 nm</td>
</tr>
<tr>
<td>Atomic density</td>
<td>5.00 × 10^{22} atoms/cm^3</td>
</tr>
<tr>
<td>Density at 300 K</td>
<td>2.329 g/cm^3</td>
</tr>
<tr>
<td>Volume increase at trans. from liq. to solid</td>
<td>+ 9.1 %</td>
</tr>
<tr>
<td>Specific heat (300 K)</td>
<td>0.713 J g^{-1} K^{-1}</td>
</tr>
<tr>
<td>Thermal expansion (300 K)</td>
<td>2.6 × 10^{-6} K^{-1}</td>
</tr>
<tr>
<td>Thermal conductivity (300 K)</td>
<td>1.5 W cm^{-1} K^{-1}</td>
</tr>
<tr>
<td>Melting point</td>
<td>1687 K</td>
</tr>
<tr>
<td>Boiling point</td>
<td>3504 K</td>
</tr>
<tr>
<td>Latent heat of fusion</td>
<td>50.66 kJ/mol</td>
</tr>
<tr>
<td>Heat of evaporation</td>
<td>385 kJ/mol</td>
</tr>
<tr>
<td>Combustion heat, ΔH^o (Si/SiO_2) (298 K)</td>
<td>-911 kJ/mol [2]</td>
</tr>
<tr>
<td>Bulk modulus (300 K)</td>
<td>97.84 Pa</td>
</tr>
<tr>
<td>Band gap (300 K)</td>
<td>1.126 eV</td>
</tr>
<tr>
<td>Electron mobility</td>
<td>1440 cm^2 V^{-1} s^{-1}</td>
</tr>
<tr>
<td>Hole mobility</td>
<td>484 cm^2 V^{-1} s^{-1}</td>
</tr>
</tbody>
</table>

1.2 Uses of Silicon

In metallurgy and chemistry important portion of the silicon is consumed as alloying element and as reducing agent in metal industry. The purity of the silicon that is used directly in metal industry is about 98 %. Silicon with purity of about 98 % is called as metallurgical grade silicon (MG-Si). A graph showing relative distribution of uses of MG-Si is schematically given in Figure 1.1 [3]. MG-Si is mostly used in aluminum industry. It is also used in steel, silicone and semiconductor industries. In steel industry, ferrosilicon or directly MG-Si can be used as a source of silicon for alloying and deoxidation. Silicones are polymers and contain silicon together with carbon hydrogen and oxygen in the chemical structure. It has very wide application areas such as medical applications, cookware, and insulation. Therefore an important portion of silicon is used in the production of silicones. Portion of silicon that is used for the semiconductor industry is small. This is due to the small scale of parts in electronic industry. However, its technical...
importance is crucial. Silicon is widely used in electronics industry due to excellent electronic properties. Mass production of electronic chips and photovoltaic cells are almost based on silicon. There are other uses in solid state electronics such as in production of transistors, liquid crystal displays, diodes, etc. MG-Si must be further purified for semiconductor applications.

Beside silicon, ferrosilicon is also used in metal industry. It is a ferroalloy which includes silicon in it. Its grade is changing from 15 % to 90 % according to silicon content. Ferrosilicon is used in steelmaking and foundries as a source of silicon to improve quality of steel, and to remove oxygen from the steel. High purity ferrosilicon; with low aluminum and low carbon contents, are used in the production of special steel qualities.

![Figure 1.1: Uses of metallurgical grade silicon in industry is schematically shown by a pie diagram [3].](image)
Above areas are the primary uses of silicon. In addition to these, silicon carbide is widely used as an abrasive material. The compounds of silicon with a metal, which are called as silicides, can be used for different applications. For instance molybdenum disilicide is very resistant to oxidation and used as heating elements. Other special uses of silicon compounds exist also. When silicon is treated with chlorine, SiCl₂ forms. If it is mixed with NH₄OH a dense white smoke of the metasilicic acid and ammonium chloride is obtained. This mixture is used for skywriting [4].

1.3 History of Silicon

The name silicon comes from the Latin word silex which means flint. Flints are made of silicon dioxide. Silica is very difficult to decompose into its elements. Therefore silica was supposed to be an element for a long time. Ancient people used silicon compounds to produce glass. In 1700s attempts were made to obtain silicon in elemental form. Just after 1800, Humphrey Davy succeeded to decompose soda and potash into metallic sodium and potassium by electrolysis. By using potassium as the reducing agent; Davy and in Paris Gay-Lussac and Thenard tried to decompose substances that were previously indecomposable and discovered new elements. Gay-Lussac and Thenard were able to obtain silicon in 1811. However it was not impressive at all until Berzelius obtained relatively pure silicon with the reduction of SiF₄ by using potassium metal in 1824 [4].

Coarse-grained silicon was obtained by fusion electrolysis of silicon-containing NaAlCl₄ by Sainte-Claire Deville in 1854 [1]. Other important developments were carried by Wöhler (1855), Winkler (1864), Scheid (1899) and Kühne (1902).

In 1808, Berzelius produced ferrosilicon by heating silica, carbon and iron together [5], but commercial production of ferrosilicon began in the early 1900s as a byproduct of calcium carbide production [1]. The most common commercial production method of metallurgical grade silicon is based on the method of
Berzelius wherein silica is reduced by carbon. Usage of silicon as a solar cell material could not be achieved until 1941 when Russell Ohl from Bell Laboratories invented the first silicon solar cell [6].

1.4 Economy of Silicon

Production of silicon increased steadily, except some fluctuations, between the years 1964 and 2007 (Figure 1.2 [7]). This increase can be attributed to industrialization of the world. Since an important portion of silicon consumed in metallurgy and chemistry as alloying element and reducing agent, prices and production amount of silicon metal are generally dependent on the changes in demand and supply of aluminum, steel and chemical industries. Variation of silicon prices between the years 1961 and 2007 is given in Figure 1.3 [7]. High purity silicon prices are excluded in this figure.

As being an alloy of silicon, ferrosilicon has an important role in steel industry and foundries. Ferrosilicon production is as much as silicon production on the weight basis. In 2001 world production of ferrosilicon was 4.040 million tons and increased to 5.660 million tons in 2004 [8] and to about 6.06 million tons in 2008 [9]. China is the major ferrosilicon producer in the world. Producers of ferrosilicon on the country basis in 2008 is illustrated in Figure 1.4 [9].

Although only a few percentages of total silicon production are used for electronic applications, requirement for high purity silicon for the electronic applications and photovoltaic applications is increasing. Trend of this demand is shown in Figure 1.5 [10]. The values after 2007 are predicted values in this figure. Especially for the photovoltaic applications a significant increase in demand of high purity silicon is expected.
Figure 1.2: World silicon production between the years 1964 and 2007 [7].

Figure 1.3 Silicon prices between the years 1961 and 2007 (high purity silicon prices are excluded) [7].
Figure 1.4: Ferrosilicon production percentages of the countries in 2008 [9].

Figure 1.5: Demand for silicon that is used for electronic and photovoltaic industry given in kilotons (reproduced from [10]).
Polycrystalline solar grade silicon is used for the photovoltaic applications mostly. Production of polycrystalline solar grade silicon is far from meeting the demands. Estimated production, demand and shortage are given in Table 1.2 [11]. Here it was foreseen that the shortage will occur for the next 4 years and continue further. Due to this shortage, high purity silicon prices are very high. The kilogram price for the high purity silicon was $50 in 1992 [1] and it rose to between 100 to $300 [12] in 2007.

Table 1.2: Production, demand and shortage for polycrystalline solar grade silicon (the values after 2007 are predicted values) [11]

<table>
<thead>
<tr>
<th>Year</th>
<th>Production (Ton)</th>
<th>Demand (Ton)</th>
<th>Shortage (Ton)</th>
</tr>
</thead>
<tbody>
<tr>
<td>2005</td>
<td>30,680</td>
<td>33,850</td>
<td>3,170</td>
</tr>
<tr>
<td>2006</td>
<td>33,390</td>
<td>39,520</td>
<td>6,130</td>
</tr>
<tr>
<td>2007</td>
<td>37,500</td>
<td>46,900</td>
<td>9,400</td>
</tr>
<tr>
<td>2008</td>
<td>51,000</td>
<td>62,940</td>
<td>11,940</td>
</tr>
<tr>
<td>2009</td>
<td>73,500</td>
<td>81,340</td>
<td>7,840</td>
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<tr>
<td>2010</td>
<td>96,500</td>
<td>103,440</td>
<td>6,940</td>
</tr>
<tr>
<td>2011</td>
<td>115,200</td>
<td>121,560</td>
<td>6,360</td>
</tr>
<tr>
<td>2012</td>
<td>142,000</td>
<td>148,150</td>
<td>6,150</td>
</tr>
<tr>
<td>2013</td>
<td>168,000</td>
<td>173,200</td>
<td>5,200</td>
</tr>
</tbody>
</table>
CHAPTER 2

LITERATURE REVIEW

2.1 Industrial Production of Silicon

2.1.1 Metallurgical Grade Silicon Production

Silicon has been produced with the same principle since the beginning of the twentieth century. Although the production principle has remained the same, production practice has improved significantly with use of larger furnaces, better material handling and control of operations. As a result of this, energy consumption has decreased. Silicon is produced by carbothermic reduction of silica between the temperatures 1900°C and 2100°C. Overall reaction is given as follow:

$$\text{SiO}_2(s) + 2\text{C}(s) = \text{Si}(s) + 2\text{CO}(g)$$  \hspace{1cm} (1)

It is also possible to produce silicon by aluminothermic reduction of SiO₂. However, it is not economical due to comparatively higher price of aluminum. Gibbs energy changes of selected reactions, important in silicon production, as a function of temperature are given in Figure 2.1 [1].

Raw materials for the production are quartzite and/or lumpy quartz, metallurgical grade coal as well as charcoal and coke, and wood chips for good ventilation of charge. Purity of these starting materials is important for the purity of the product. Generally the purity of produced silicon after carbothermal process is 98 %. Typical impurity levels of metallurgical grade silicon is given in Table 2.1 [3].
Figure 2.1: Gibbs energy changes of some reactions showing production of silicon from SiO\textsubscript{2} and silicon tetrahalides (reproduced from [1]).
Table 2.1: Typical impurity levels for metallurgical grade silicon in atomic parts per million (ppma) [3]

<table>
<thead>
<tr>
<th>Element</th>
<th>Concentration (ppma)</th>
</tr>
</thead>
<tbody>
<tr>
<td>Al</td>
<td>1200-4000</td>
</tr>
<tr>
<td>B</td>
<td>37-45</td>
</tr>
<tr>
<td>P</td>
<td>27-30</td>
</tr>
<tr>
<td>Ca</td>
<td>590</td>
</tr>
<tr>
<td>Cr</td>
<td>50-140</td>
</tr>
<tr>
<td>Cu</td>
<td>24-90</td>
</tr>
<tr>
<td>Fe</td>
<td>1600-3000</td>
</tr>
<tr>
<td>Mn</td>
<td>70-80</td>
</tr>
<tr>
<td>Mo</td>
<td>&lt;10</td>
</tr>
<tr>
<td>Ni</td>
<td>40-80</td>
</tr>
<tr>
<td>Ti</td>
<td>150-200</td>
</tr>
<tr>
<td>V</td>
<td>100-200</td>
</tr>
<tr>
<td>Zr</td>
<td>30</td>
</tr>
</tbody>
</table>

Electric-arc furnaces are used for industrial carbothermal production of silicon and also for production of ferrosilicon. The raw materials fed into this furnace are reduced by using graphite electrodes.

Purity of electrodes also plays role for the purity of silicon. However it is not as important as the purity of raw materials. Schematic drawing of electric-arc furnace is given in Figure 2.2.

For the production of 1 ton of metallurgical grade silicon, 2.9 to 3.1 tons of quartz or quartzite, 1.2 to 1.4 tons of coke and 1.7 to 2.5 tons of charcoal and wood are consumed [1]. In addition to raw materials graphite electrodes are also consumed (120 to 140 kg/t of silicon). Energy consumption of this process is 12.5 to 14 MW·h/t of silicon.
Figure 2.2: Schematic drawing of electric-arc furnace for silicon production (a) raw materials input (b) electrode holder (c) contact for electricity (d) electrode (carbon) (e) electrode for tapping (reproduced from [1]).

Although metallurgical grade silicon has about 98% purity, it can be increased by starting with purer raw materials and improved furnace design and production process. It is possible to achieve 99.99% purity by an improved arc furnace which is called as direct arc reactor (DAR). Dow Corning Company introduced a patented process for the production of solar grade silicon by using DAR and starting with purer reducing agent and quartz [13].

Silicon can also be produced from silicon tetrafluoride. Silicon tetrafluoride is a byproduct of superphosphate fertilizer. The ore is phosphate rock which contains CaF₂. HF is obtained from this compound by treating it with H₂SO₄. Finally SiF₄ is obtained after the reaction of SiO₂ with HF. Purification of SiF₄ is done by passing it over iron at about 800°C [1, 14] or through concentrated sulfuric acid [14]. Air and
SO$_2$ gases are removed by this purification process [1]. The reaction for obtaining silicon powder from SiF$_4$ is:

\[
\text{SiF}_4(g) + 4\text{Na}(l) \rightarrow \text{Si}(s) + 4\text{NaF}(s) \quad (2)
\]

Here, the reaction yields NaF which is four moles for every mole of silicon produced. Therefore, this production method may become economical if byproduct NaF can be sold.

2.1.2 High-Purity Silicon Production

Electronic applications of silicon require higher purity than metallurgical grade silicon. Therefore metallurgical grade silicon is further purified by some techniques including HCl treatment to produce trichlorosilane and chemical vapor deposition. High purity silicon can be divided into two grades. One is solar grade silicon, and the other is electronic grade silicon. Both of them can be referred as semiconductor grade silicon. However electronic grade silicon has higher purity. Its purity can be up to 99.9999999 % (called as 9N). On the other hand solar grade silicon purity is 99.999 % (5N). Purity of silicon depends on the process that is applied to metallurgical grade silicon. In Figure 2.3, flow chart for the production of high purity silicon is given.

Upgrading of metallurgical grade silicon can be done by using inductive plasma technique under the flow of oxygen and hydrogen mixture [15] or by using solar radiation under the flow of argon and H$_2$O at a reduced pressure [16]. Boron and phosphorus impurities are removed by this way. Some companies have their own processes for the production of upgraded metallurgical grade silicon like Timocco and Arise. Producing higher purity silicon from upgraded metallurgical grade silicon requires some additional purification steps. Silicon metal is converted into compounds like, SiHCl$_3$ and SiCl$_4$ in Siemens process. To obtain one or both of
Metallurgical grade Silicon (MG – Si)

Dissolve in HCl + Distillation

Various gases

Chemical refinement

Hydrogen

Siemens Process

Modified Siemens Process

HCl

Trichlorosilane SiHCl₃

High purity silicon ~9N

High purity silicon ~6-7N

Upgraded MG - silicon >5N

Figure 2.3: High purity silicon production flow chart [17].
these compounds, metallurgical grade silicon is ball milled and reacted with anhydrous HCl in a fluidized bed reactor at about 575 K [18]. Flow chart of this process is given in Figure 2.4. Product after this process is approximately 90 % SiHCl\(_3\) and the rest is mainly SiCl\(_4\). The SiHCl\(_3\) formation reaction for this process is given as follows:

\[
\text{Si(s)} + 3\text{HCl(g)} = \text{SiHCl}_3(g) + \text{H}_2(g) \quad (3)
\]

Another compound for production of high purity silicon is silane (SiH\(_4\)). Silane can be produced from two different resources. One is obtained from recycling of chlorosilanes. The other was developed by Ethyl Corporation [18] which uses, H\(_2\)SiF\(_6\), a byproduct of superphosphate fertilizer.

Figure 2.4: Flow chart of production of SiHCl\(_3\); (a) fluidized bed reactor; (b) filter for dust; (c) condenser; (d) Tanks; (e) low-boiling impurities distillation; (f) high-boiler distillation (g) tanks; (h) product storage tanks (reproduced from [1]).
Renewable Energy Corporation (REC) developed a new process to purify silicon called Fluidized Bed Reactor Process [19]. Raw material for this process is silane. Reaction, taking place in fluidized bed reactor is given as follows:

\[ \text{SiH}_4(g) = \text{Si}(s) + 2\text{H}_2(g) \]  

(4)

Purity of silicon is not as high as in Siemens process. However this process does not produce byproduct and it is cheaper than Siemens process.

Upgraded metallurgical grade silicon and silicon produced by modified Siemens processes (like REC silicon) can be used for solar cell modules, although efficiency of modules changes according to purity of silicon. However, higher purity is required for electronic applications. Furthermore, electronic grade silicon can be considered for the high efficiency solar cells.

Commercial electronic grade silicon is produced by Siemens process. In this process a starting silicon rod is used. Trichlorosilane and hydrogen gases react at about 1375 K and silicon is deposited onto starting silicon rod at this temperature. Reaction is given as follows:

\[ 4\text{SiHCl}_3(g) + 2\text{H}_2(g) = 3\text{Si}(s) + \text{SiCl}_4(g) + 8\text{HCl}(g) \]  

(5)

Chemical vapor deposition system for this process is given in Figure 2.5. The byproduct \( \text{SiCl}_4 \) can be recycled to form trichlorosilane.

All of these processes result in high purity polycrystalline silicon. Generally electronic applications like electronic chips and microprocessors require single crystalline and higher purity silicon. Two crystal growth methods are used in industry for this purpose. One is Czochralski crystal growth the other is float-zone crystal growth.
In Czochralski method a single crystal silicon seed dipped into silicon melt and held in the crucible. With a suitable pulling speed and crucible rotation, single crystal of desired shape silicon can be produced. In float–zone crystal growth method there is no crucible to hold the melt. Starting material for this method is a polycrystalline silicon rod. This rod is melted by an induction coil. A large melt drop is created and a slim seed crystal is brought in contact with this melt by moving the seed crystal through the narrow opening which is in the center of the induction coil. Since there is no crucible in this method impurity level of silicon is lower than that of Czochralski method.
2.2 Disadvantages of Current Processes and Alternative Processes

Silicon is most widely used semiconductor for the solar cell applications. For these applications purity is the major concern. To obtain high purity silicon some special techniques and instruments are used as mentioned above. Therefore prices are high and solar cells are not widely used for energy production. Processes for production and purification of silicon should be improved and it should become cheaper to use solar cells for daily applications. Today’s silicon production and purification has certain disadvantages:

1) Production and purification steps are carried out separately. There are some direct methods for the production of solar grade silicon, but their energy consumption is high. For instance in Dow Corning process energy consumption varies between 25.7 kWh and 78 kWh per kilogram of silicon [13].

2) Siemens and modified Siemens processes depend on MG–Si and require silicon to be converted into compounds and then converted to elemental silicon at relatively high temperatures. Therefore they are expensive and different facilities are needed.

3) It is difficult to handle chemicals that are used (HCl, H₂) and produced (silane and trichlorosilane) to obtain high purity elemental silicon.

4) Due to high energy consumption, these processes are not environmental friendly.

Electrochemical methods were considered as an alternative process for the production of high purity silicon. Electrodeposition of silicon was first reported in 1854 [20]. Then, 99.999 % purity silicon was deposited onto silver by electrolysis of K₂SiF₆-floride systems at 745°C in 1980 [21]. However, major drawback of this process was growth rate. It was only 45 μm/hour. Another attempt was made to
obtain silicon by electrolysis of SiO₂ from BaO-SiO₂-BaF₂ melt at temperatures above 1415°C in 1981 [20]. Purity of silicon, obtained in this study was 99.97%. These processes and other processes related with the electrochemical production of silicon [22-27] were not industrialized.

2.3 FFC Cambridge Process

Molten salt electrolysis is found to be the best possible route, as in the case of Al₂O₃, for reduction of very stable compounds. However this method is suitable for metals that are deposited in liquid state. This means that the melting temperature of metal should be less than the reduction temperature of its oxide. For the metals that have higher melting point molten salt electrolysis become difficult to carry out. In this case, electrowinning is an option. However, it has its own problems like dendritic deposition which is prone to oxidation.

Removal of non-metallic impurities like oxygen and sulfur by cathodic refining technique was first reported by Ward and Hoar [28]. They successfully removed oxygen, sulphur, tellurium and selenium from molten copper in molten barium chloride by the electrochemical technique. Similar to this application, some techniques were developed by Okabe et. al. for removal of oxygen from titanium [29, 30]. Molten calcium chloride was used as electrolyte in their studies. Schematic drawing of cell assembly for cathodic refining technique is given in Figure 2.6.

A novel process for production of metals and alloys from their solid oxides in molten salts by electrolysis was reported in 1997 [31]. This process is called as FFC (Fray–Farthing–Chen) Cambridge process. It was first discovered by reducing solid oxide thin films on titanium foil in molten calcium chloride bath by electrolysis [31]. Electroreduction of high melting transition metal oxides and actinides is more suitable for this process [32]. Also it was claimed that this process is more environmental friendly and cost efficient. Although process is a high temperature electrolysis process to produce metals or alloys from their oxides, sulphides,
carbides or nitrides, studies have focused on mostly electroreduction of solid oxides so far.

FFC cell generally consists of a graphite anode, metal oxide cathode and molten salt electrolyte. The major component of the electrolyte is generally CaCl₂. Cell arrangement of FFC cell is very similar to cathodic refining cell arrangement [28-30]. Pellets subjected to reduction can be either placed at the bottom of a conductor crucible (Figure 2.7(a)) or attached to a wire (Figure 2.7(b)) that act as cathode for the cell assembly of FFC process. Electrolysis is conducted by applying a potential between the graphite anode, and the cathode. This potential is lower than the decomposition potential of molten salt and higher than the decomposition potential of metal oxide. Oxygen present in metal oxide converted to oxygen ion and then

\[
\text{Graphite} \quad \text{Impure Metal containing oxygen or sulphur} \quad \text{Graphite} \\
\text{Alkaline earth chloride electrolyte}
\]

Figure 2.6: Schematic drawing of cathodic refining cell assembly.
Figure 2.7: Schematic drawings of cell assemblies of FFC Cambridge process. (a): pellets are placed at the bottom of the crucible that act as cathode and (b): pellets are attached to a cathode wire.
with the effect of applied potential, oxygen ions move towards the graphite anode during the electrolysis. Oxygen ions discharged at the graphite anode forms CO or CO₂. General form of the reactions is as follows:

\[ M_{x}O_{y}(s) + 2ye^- = xM(s) + yO^{2-} \text{ (cathode)} \]  
\[ yO^{2-} + yC(s) = yCO(g) + 2ye^- \text{ OR } yO^{2-} + y/2C(s) = y/2CO_2(g) + 2ye^- \text{ (anode)} \]

If an anode which is inert to oxygen is used, oxygen will be produced at anode and the overall reaction for this case is given as:

\[ M_{x}O_{y}(s) = xM(s) + y/2O_2(g) \]  

### 2.4 Silicon Production by the FFC Cambridge Process

Electrodeoxidation of SiO₂ plate to Si was first reported by Nohira and his coworkers [33]. In this study, pinpoint and bulk electrodeoxidation studies were carried out at 850°C in CaCl₂ molten salt. Cathode was made out of a contacting material, molybdenum wire in their case, and SiO₂ plate attached to it. They successfully formed a layer of silicon on the surface of the SiO₂ plate after 1 hour of electrolysis. The reduction process of SiO₂ at the cathode can be expressed as:

\[ SiO_2(s) + 4e^- = Si(s) + 2O^{2-} \]  

In the study of Yasuda et. al. [34] direct electrochemical reduction of SiO₂ plate to Si was confirmed at 1.25 V or more negative potentials (versus Ca²⁺/Ca). Mechanism of direct electrolytic reduction of solid SiO₂ to silicon in molten calcium chloride was reported by Yasuda et. al. [35]. They claimed that oxygen atom in metal oxide receives electrons and converted to O²⁻ ion at the conducting material. Then this ion is removed from the cathode towards the graphite anode by diffusion in molten CaCl₂. Due to decrease in molar volume, when SiO₂ is converted to Si, the vacant
space formed is filled in by molten calcium chloride. Therefore new three phase interface is established at electrode between silicon, silicon dioxide and molten calcium chloride. This procedure is repeated until whole SiO$_2$ is reduced to Si. Schematic drawing of this proposed mechanism is given in Figure 2.8 [35].

In this electrodeoxidation process transportation of O$^{2-}$ ions was reported as rate determining step in the study of Yasuda et. al. [35]. Furthermore, precipitation of CaO in the catholyte at more negative potentials was attributed to the O$^{2-}$ ion saturation due to limited transportation in the electrolyte [36]. It is a known fact that, O$^{2-}$ ions carried to anode/electrolyte interface reacts with graphite to produce CO and/or CO$_2$ when graphite is used as anode. In this case calcium carbonate (CaCO$_3$) formation reported [37] in CO$_2$ containing molten CaCl$_2$–CaO melts was
considered as the result of chemical reaction between CaO and CO$_2$ in the electrolyte.

Electrochemical reduction of porous SiO$_2$ pellet was first reported by Jin and his coworkers [38]. They claimed that reduction of the pellet with 1.3 cm diameter and 0.5 cm thickness was completed at 850°C in molten CaCl$_2$ in 4 hours. The product was grey silicon powder. In another study, Yasuda et. al. [39] compared the reduction rates of dense SiO$_2$ plate and porous SiO$_2$ pellet. They reported that reduction rate of dense SiO$_2$ plate was faster than that of porous SiO$_2$ pellet. They also succeeded to increase the reduction rate of porous pellet by adding small amount of Si into porous SiO$_2$ pellet. Addition of 10 % Si into porous pellet resulted in faster reduction rate than dense SiO$_2$ plate at 1.00 V negative potentials (versus Ca$^{2+}$/Ca).

A new production process of solar grade silicon by direct electrochemical reduction method was proposed by Yasuda and his coworkers [40]. Flowchart of this process is given in Figure 2.9 [40]. They used silicon plate as cathode contacting material to prevent metal contamination from conducting material. The purity of silicon was reported as 99.80 at.%, due to metal contamination from stainless steel vessel. On the other hand, the concentrations of boron and phosphorus were reported as very low which shows the potential of direct electrochemical reduction process for the solar grade silicon production.

Mo wire [33-35, 39, 41], Ni metal [36-38], or silicon plate [40] were used as cathode contacting materials in direct contact with insulating SiO$_2$ plate or pellet to achieve reduction in the studies mentioned above. Yet, the reported results do not show adequate criticism of the use of above metallic materials, except silicon, in the environments formed in these tests. Especially in the case of nickel and molibdenum that is in contact with elemental silicon, the formations of Ni$_x$Si$_y$ and Mo$_x$Si$_y$ intermetallics are inevitable [42, 43]. In spite of this fact, only one study [37] mentioned that problem.
In addition, there are disagreements about the rate of SiO₂ reduction. Only one of the reports [38] claim complete reduction of porous SiO₂ pellet to Si metal. Besides, they claimed that the reduction was completed in 4 hours although there is a study which reported [39] much slower reduction of porous SiO₂ pellet than SiO₂ plate. Moreover, all other observations [33-37, 39-41] give results of incomplete reductions.

Another conflict in the literature is the color of the product. Reported colors of reduced products were brick-red [37], brownish [33, 35] as seen from photographs, and grey [38].

**Figure 2.9: The flowchart of proposed process for SOG-Si production [40].**
2.5 The Objective of This Research

As stated above, current industrial production of solar grade silicon has many steps and difficulties. Therefore a new electrochemical method based on FFC Cambridge process for the solar grade silicon production has been studied and potential of this method has been reported by researchers. However, there are considerable ambiguities about the behavior of cathode contacting materials, time required for complete reduction, and even the color of the produced silicon in the literature.

To resolve the conflicts regarding the behavior of cathode materials, the rate of reduction and the color of reduced products, electrochemical reduction of SiO$_2$ pellets and plates were performed in molten salt electrolytes. Besides, effects of temperature and particle size of the starting SiO$_2$ powder were investigated in molten CaCl$_2$ and CaCl$_2$-NaCl salt mixtures to optimize the process.
CHAPTER 3

EXPERIMENTAL

3.1 Experimental Setup

3.1.1 Cell Assembly

The schematic drawing of the cell assembly is given in Figure 3.1. Different cathode and anode designs were tested in preliminary experiments and improved design, that minimizes undesirable reactions, was used throughout this thesis. Most of the experiments were conducted by using porous silicon dioxide pellet as cathode. But bulk fused quartz plates were also used as cathode in some of the experiments. The same cell assembly was used for both cathodes, but small differences in procedure will be given for each cathode later.

Silicon dioxide pellet, forming the cathode of the cell, was sandwiched between two contacting metal plates that formed the cathode assembly. Plates were stainless steel, except in experiments that involved the study of the behavior of nickel cathode plate. One of the plates was welded to the end of the stainless steel wire (Ø: 3 mm, height: 60 cm) and placed under the pellet. The other plate was placed on top of the pellet. To hold this sandwiched structure together, a wire (Kanthal D, Ø: 0.15 mm) was wrapped around the plates. Two different procedures were employed to place the SiO₂ pellets in to the cathode assembly. Silica pellets were directly used in one, they were covered with a Kanthal wire (Kanthal D, Ø: 0.15 mm) mesh in the other procedure. The tests to examine the behavior of cathode contacting materials were done by using pellets without the wire mesh to have contact surface between
Figure 3.1: Schematic drawing of cell assembly.
the pellet and the contacting materials as much as possible. The wire mesh was used to decrease the contact surface between the pellet and contacting metal plates at the same time increase the electrolyte volume at SiO$_2$-cathode metal conductor-electrolyte interface. This procedure was expected to increase oxygen transport from the cathode and yield higher reduction rates. The porous pellet was replaced by fused quartz plate with Kanthal wire mesh in experiments with bulk silica cathode.

A 15 cm long and 13 mm diameter graphite (Alfa Aesar A10134) rod that was attached to a 3.5 mm diameter wire (Kanthal A-1) at the top and extended out of the cell vessel was forming the anode. Both anode and the vertical cathode lead wires were covered with quartz and alumina insulators, respectively to prevent short-circuiting of electrodes and undesirable interactions with the gases formed inside the cell vessel. An alumina crucible (10 cm long, 4.5 cm outside diameter) containing electrolytic cell was placed to the bottom of a quartz vessel (50 cm long, 5 cm outside diameter). Teflon lid was used to cover the top of the quartz vessel. There were four holes on the Teflon lid, two of them (Ø: 3.5mm) for the electrode connections.

Other two holes (Ø: 7 mm) were for argon inlet and gas outlet. Rubber o-rings were used in each hole to prevent gas leakage and at the same time enable vertical movement of electrodes. The vertical movements of electrodes were necessary to mix the electrolyte for homogenization, place them inside the alumina crucible at the beginning and move them outside the crucible at the end of each experiment.

Quartz cell vessel, that could withstand high temperatures and is chemically inert to corrosive environment formed inside the cell, was put into a vertical tube furnace. About 15 cm of the quartz cell vessel remained outside the furnace at the top in order to allow the necessary electrode movements and to make electrical and gas connections at the temperatures close to room temperature.
3.1.2 Auxiliary Apparatus

Schematic drawing of auxiliary apparatus is given in Figure 3.2. Agilent N6700B low profile MPS main frame with N6773A direct current (DC) power module, power supply was used as a power source. The applied cell potential and the applied current were collected by a computer that was attached to power source via a Visual Basic code embedded into Microsoft Excel during experiments. Lindberg LHTF3226 Kanthal wire wound vertical tube furnace was used to heat up the cell assembly. To control the furnace temperature and ramp/dwell combinations, an Eurotherm 818P controller was used. All experiments were conducted under the flow of 100 ml/minute argon gas. Argon gas was dried by a drying column containing Drierite® (CaSO₄) prior to admission into cell vessel through the gas inlet port. Moreover, argon gas was used as carrier gas to purge gaseous electrolysis products. A photograph of the experimental setup together with auxiliary apparatus is given in Figure 3.3.

3.2 Experimental Procedure

3.2.1 Cell Feed Preparation

For most of the experiments, commercially available SiO₂ powder (Fluka 00653 purum p.a.; ≤230 mesh) was used to prepare porous pellet for cathode. Fused quartz plate (QSIL AG Quarzschmelze Ilmenau, Germany) was used in experiments with bulk SiO₂. SiO₂ powder was characterized by scanning electron microscope (SEM) and x-ray diffractometer (XRD). The SEM photograph and XRD results of starting SiO₂ powder are given in Figure 3.4 and Figure 3.5, respectively. XRD result of the starting material revealed that the only phase exist in the powder was quartz. According to SEM photograph, particle size of the powder was below about 64 μm, as given by specifications, and particles had irregular shape.
A: Argon Cylinder  
B: Flowmeter  
C: Drying Column  
D: Argon Inlet  
E: Electric connections  
F: DC Power Supply  
G: Gas Outlet  
H: Verticle Tube Furnace  
I: Thermocouple  
J: Computer

Figure 3.2: Schematic drawing of the auxiliary apparatus.
XRD pattern of the fused quartz is given in Figure 3.6. The figure exhibits characteristic X-ray diffraction of amorphous patterns with a very broad peak in the case of bulk SiO$_2$ plate.

About 1.20 grams of SiO$_2$ powder was manually pressed under 1.5 tons of load to form a porous cylindrical pellet. The green pellets were then sintered at 1300°C for 2 hours. The average diameter of the pellets was 15 mm and the height was about 5 mm. One porous SiO$_2$ pellet was placed between two metal plates to form the cathode, as explained above, for each experiment.
Figure 3.4: SEM photograph of starting SiO$_2$ powder.

Figure 3.5: XRD analysis of starting SiO$_2$ powder.
CaCl₂ (Riedel-de-Haën 12022) and CaCl₂-NaCl (Riedel-de-Haën 13423) salt mixtures were used as electrolyte. Composition was adjusted as 70 mole% CaCl₂ and 30 mole% NaCl for the experiments conducted in CaCl₂-NaCl salt mixture. Both salts were dried before the experiments without producing the hydroxides and the oxides of the salts.

Phase diagram of CaCl₂-H₂O system at 10⁻³ atmosphere HCl partial pressure [44] is given in Figure 3.7. In this figure possible phase boundaries are shown by dashed lines. The drying procedure was conducted in accord with below phase diagram to obtain anhydrous, oxide free CaCl₂ without forming the solution. Therefore, CaCl₂ salt was heated at a rate of 8°C/hour up to 400°C. It was kept at that temperature for 24 hours. The system was under vacuum during the whole drying process.
Figure 3.7: The equilibrium diagram for the CaCl₂–H₂O system showing possible phase boundaries between the hydrates and the solution by dashed lines at an HCl partial pressure of 10⁻³ atm. (reproduced from [44]).

NaCl was also dried for the experiments that used CaCl₂–NaCl salt mixture as electrolyte. It was just heated to 110 °C and kept at that temperature for 4 hours to remove physical moisture. Any other drying process was not necessary for NaCl, because unlike CaCl₂, equilibrium partial pressure of H₂O to form NaOH is very high, as seen in Figure 3.8.

Figure 3.8: Equilibrium diagram of NaCl–H₂O system at an HCl partial pressure of 10⁻³ atm. (reproduced from [44]).
3.2.2 Cell Operations

Alumina crucible containing 100 grams of salt or salt mixture was placed into the quartz vessel. Teflon lid together with cathode and anode assemblies was then placed to the open end of the vessel to cover at the top. The quartz vessel containing the cell assembly was placed into the vertical tube furnace. Argon inlet and gas outlet connections were established. The furnace was heated up to 400°C with a ramp rate of 5°C/min. Then the temperature was adjusted to 850°C when only CaCl₂ salt was used and to 850°C, 800°C and 750°C when CaCl₂-NaCl salt mixture was used as electrolyte. The whole heating process and electrolysis experiments were conducted under continuous flow of 100 ml/minute argon. After reaching the desired temperature, sufficient time was given for the stabilization of the temperature and homogenization of the salt mixture. Then electrodes were immersed into the electrolyte. Electrical connections of cathode and anode were established to DC power supply. The power supply was turned on to start electrochemical reduction reaction. The applied potential for the experiments was 2.8 V. This value is lower than the decomposition potentials of CaCl₂ (E° = -3.4 V) and NaCl (E° = -3.37 V).

The electrochemical reduction was continued for 4 to 16 hours. The applied voltage and the current were digitally collected by using a computer. The cell vessel was flushed by increasing flow rate of argon gas at the end of the each experiment. Then, experiments were terminated by turning off the DC power supply. Electrodes were then lifted out of the electrolyte and the system was cooled down under the flow of argon gas. The reduced pellets or plates were washed in ultrasonic water bed for 10 minutes. Afterwards, the reduced powder was filtered and dried. Then the sample was subjected to cleaning process in 0.1 M hydrochloric acid solution to remove calcium carbonate, which was found to be present in reduced products taken from the cathode. Finally, electrolysis products were characterized by XRD (Rigaku D/MAX2200/PC) and SEM (JEOL JSM-6400 and FEI Nova NanoSEM 430). These characterizations were also done before the HCl treatment. In addition to the
reduced powder, the materials left on the cathode contacting materials were characterized by XRD for some of the experiments.

3.3 Experimental Setup and Procedure for Cyclic Voltammetry Studies

The cyclic voltammetry studies were performed to obtain information about mechanistic steps of the electrochemical reduction. Only porous silica pellets were used in this study. The schematic drawing of the cell assembly used for this purpose, given in Figure 3.9, was obtained by modification of the cathode and introduction of a reference electrode. An additional hole was provided on Teflon lid to install reference electrode.

The SiO$_2$ pellet was prepared the same way as described in part 3.2.1. Then, the pellet was attached to a Kanthal wire by drilling a hole in the middle of the pellet to form the cathode, which was prepared to act as working electrode, and it was connected to pole W in Figure 3.9. Anode, which acted as counter electrode, was prepared the same way as described in part 3.1.1 and connected to pole C. The reference electrode which was connected to pole R of the potentiostat (Gamry Reference 3000 Potentiostat/Galvanostat/ZRA) was prepared by welding a 6 cm long tungsten wire to the lower end of a copper wire. About 10 cm of the anode, cathode and reference electrode wires were extended out of the cell vessel to allow electrical connections.

Similar to electrochemical reduction experiments; CaCl$_2$-NaCl (30 mole % NaCl) salt mixture prepared the same way as described in part 3.2.1, was used as electrolyte. After placing the cell vessel containing the cell assembly into the vertical tube furnace and making argon inlet and gas outlet connections, the furnace was heated up to 750°C under continuous flow of argon. The electrodes were then immersed into the electrolyte and connected to the corresponding poles of the potentiostat to start cyclic voltammetry study. The scan rate was adjusted as 20 mV/s by using a computer connected to control the potentiostat. The data were collected by the
computer and experiments were terminated by turning off the supply of power. Electrodes were then lifted out of the electrolyte and the system was cooled down. Results were interpreted by means of current vs. potential difference graphs.

Figure 3.9: Schematic drawing of cell assembly used for cyclic voltammetry studies.
CHAPTER 4

RESULTS AND DISCUSSION

4.1 Electrolysis of Porous SiO$_2$ Pellets

Most of the experiments in the present study were carried out by using porous SiO$_2$ pellets as cathode. In these experiments interactions of silicon produced at the cathode with cathode contacting materials, reduction rate, color of the product, and the effect of the temperature and particle size of the starting material on reduction rate were investigated.

Electrochemical reduction of porous SiO$_2$ pellets were performed at 850°C in CaCl$_2$ and at 750°C, 800°C and 850°C in CaCl$_2$–NaCl molten salt electrolytes. Two different particle sizes: smaller than 64 μm (as received) and smaller than 38μm (undersize of 38μm screen), were used. Figure 4.1 shows the current versus time graphs of these reduction experiments. In order to show these results more clearly, and associate them with the theoretical amount of reduction, W, accumulative (total) charge, Q, passing through the cell, was calculated (shown in Figure 4.2) from;

$$Q = \int_{0}^{t} I \, dt = \frac{WzF}{A} \quad (11)$$

where I is the current in amperes, t is the time in seconds, F is Faraday’s constant, z is the valence and A is the molecular weight of silicon dioxide. The theoretical total charge required for the complete reduction of a typical 1.2 gram pellet was about 7720 Coulombs (A.s) as calculated from equation (11). Effects of temperature, electrolyte composition and particle size on reduction rate can be seen in the graphs.
Figure 4.1: Current versus time graphs during the electrolysis of pellets with different particle sizes at different temperatures in different electrolytes.

Figure 4.2: Total charge versus time graphs during the electrolysis of pellets with different particle sizes at different temperatures in different electrolytes. Legends d, 1 and 2 shows the particle size, CaCl₂ electrolyte and CaCl₂-NaCl electrolyte, respectively.
of Figure 4.1 and Figure 4.2. As it is apparent from these figures, complete reduction of the pellets could not be achieved in any of the experiments. The fastest reduction rate was observed at 850°C in CaCl$_2$ salt. Addition of NaCl decreased the reduction rate at the same temperature of 850°C. All experiments, except the one conducted at 850°C in CaCl$_2$-NaCl salt mixture for 175 minutes, were conducted for 350 minutes.

The result of the test employing SiO$_2$ pellet with Kanthal wire mesh is compared with SiO$_2$ pellet without wire mesh in Figure 4.3 and Figure 4.4. Both data are from the experiments involving the same electrolyte composition, temperature, particle size and applied voltage. The graphs for the pellet without Kanthal wire mesh is repeated from Figure 4.1 and Figure 4.2. It is clear that employment of Kanthal wire mesh has increased the reduction rate by increasing oxygen transport from the cathode.

4.1.1 Behavior of Cathode Contacting Materials

As stated in part 2.4, porous SiO$_2$ pellets were reduced to silicon first by Jin and his coworkers [38]. Porous nickel foils were used as cathode lead materials and porous SiO$_2$ pellet was sandwiched between these foils. They reported successful completion of electrochemical reduction of the pellet to silicon [38] in 4 hours. In the light of this study, porous SiO$_2$ pellet was placed between two nickel plates in the present study and 2.8 V electrical potential applied between the electrodes for 4 hours. At the end of the experiment, presence of a product other than the reduced pellet was observed on the nickel cathode plate under the pellet. Figure 4.5(a) shows the XRD pattern of the material that was collected from the surface of nickel plate. XRD analysis confirmed the reduction of SiO$_2$, but also showed the presence of Ni-Si intermetallic compounds that could form by chemical reaction of silicon and nickel. This result is supported by large negative Gibbs free energy of formation: $-1600$ and $-134$ kJ/mole [42] of Ni$_3$Si$_{12}$ and Ni$_2$Si, respectively. Ni-Si phase diagram [43] and Gibbs free energy of formation of Ni$_2$Si [42] were used to calculate the Gibbs free
Figure 4.3: Current versus time graphs during the electrolysis of the pellets (1) with and (2) without Kanthal wire mesh sandwiched between two stainless steel plates. Both tests employed SiO$_2$ powder particle size less than 64 μm, CaCl$_2$-NaCl salt mixture at 750°C and 2.8 V applied potential.

Figure 4.4: Total charge versus time graphs during the electrolysis of the pellets (1) with and (2) without Kanthal wire mesh sandwiched between two stainless steel plates. Both tests employed SiO$_2$ powder particle size less than 64 μm, CaCl$_2$-NaCl salt mixture at 750°C and 2.8 V applied potential.
energy of formation of Ni$_3$Si$_{12}$. Formation of nickel silicide was also reported by Pistorius and Fray [37].

Although silicon forms stable compounds with iron, the behavior of stainless steel plates were also tested in the environments formed during these experiments. A porous SiO$_2$ pellet was placed between two stainless steel plates and reduced for 4 hours at 2.8 V. XRD analysis of the material collected from the surface of stainless steel cathode contacting material revealed the presence of Fe-Si intermetallic compounds (Figure 4.6(a)), as expected. Presence of some CaCO$_3$ was also observed in the XRD pattern.

From the observations of the amount of materials left under the reduced pellets and the intensities of peaks given in Figure 4.5 and Figure 4.6, it was deduced that the loss of silicon was less when stainless steel plates were used as cathode contacting materials.

In addition to the materials used as metallic conductors at the cathode in this study, silicon reacts with some other alternative electrode materials, like molybdenum, copper, chromium etc.. According to the phase diagrams of Mo-Si (Figure 4.7), Cu-Si (Figure 4.8), Cr-Si (Figure 4.9), silicon forms intermetallics with all these metals at the temperatures that experiments were conducted. Therefore, it is very difficult to select an electrode material that is noble to silicon. One of the commonly used electrode material graphite also forms a stable carbide compound with silicon. Since purity of the silicon is an important parameter for the production of SOG-Si, particular attention should be given the purity of the products obtained after the reduction process. These results obtained in the present study indicated that choice of the cathode contacting material is crucial for such an application aiming at production of SOG-Si. Silicon itself can be considered as a good candidate for cathode contacting material. In the study of Yasuda et. al. [40] silicon was tried as a contacting material, however desired SOG-Si purity could not be achieved even in that case.
Figure 4.5: XRD pattern of (a) the materials that was formed on nickel plate (b) Ni$_{31}$Si$_{12}$ (ICDD card no: 17-0222) (c) Ni$_5$Si (ICDD card no: 50-0779).

Figure 4.6: XRD pattern of (a) the materials that was formed on stainless steel plate (b) CaCO$_3$ (ICDD no: 5-0586) (c) FeSi (ICDD no: 38-1397) (d) Fe$_3$Si (ICDD no: 45-1207).
Figure 4.7: Phase diagram of Mo-Si (reproduced from [45]).

Figure 4.8: Phase diagram of Cu-Si (reproduced from [46]).
4.1.2 The Rate of Electrochemical Reduction

Jin and his coworkers [38] reported complete reduction of porous SiO$_2$ pellets to silicon at the end of 4 hours of electrolysis. Contrary to this study, complete reduction of porous SiO$_2$ pellets with similar geometry and dimensions under the same applied DC potential, could not be achieved in 4 hours in the present study. Only about half of the pellet was reduced at 850°C, as deduced from Figure 4.1 and Figure 4.2. In the study of Pistorius and Fray, reduction of the porous SiO$_2$ pellets (Ø: 13.1 mm, height: 7.1 mm) to Si was achieved, but unreduced CaSiO$_3$ was reported. Their experiment probably continued for at least 16 hours as can be deduced from their current versus time graphs. The presence of CaSiO$_3$ in their study may be the result of the reaction between the pellet and CaO.

Figure 4.9: Phase diagram of Cr-Si (reproduced from[46]).
Electrolysis of porous SiO$_2$ pellets with wire mesh was performed at 750°C by using 2.8 V applied potential for 4, 8 and 16 hours to determine the required time for complete reduction in CaCl$_2$-NaCl salt mixture. In the experiments that continued for 4 and 8 hours, the products contained unreduced SiO$_2$ together with Si and CaCO$_3$. XRD analysis of reduced pellet after 8 hours of electrolysis and HCl treatment is given in Figure 4.10. Formation of calcium carbonate was thought to be due to the reaction between CaO and CO$_2$ which was the product of graphite and O$^-$ ion carried to anode in the electrolyte. CaO is normally present in CaCl$_2$ as it forms during the drying process. CaCO$_3$ formation in CO$_2$ containing CaCl$_2$-CaO melts was reported before [37] and the reaction has negative standard Gibbs energy change [42].

The complete reduction of pellets (Ø: 15 mm, height: 5 mm) were obtained in 16 hours in the present study (see Figures 4.3 and 4.4). XRD analysis of the reduced products (Figure 4.11) showed the presence of neither the unreduced SiO$_2$ nor CaSiO$_3$. Only silicon and CaCO$_3$ were present. SEM image of this product is given in Figure 4.12. Absence of CaSiO$_3$ in all results (4, 8 and 16 hours) of the present study may be attributed to low activity of CaO in anhydrous CaCl$_2$ used in this study. CaO activity in CaCl$_2$ was higher in the work of Pistorius and Fray [37] because they intentionally added CaO to the electrolyte.

4.1.3. Properties of Produced Silicon

After cleaning the product from calcium carbonate by HCl treatment, XRD analysis (Figure 4.13) confirmed that the final product was silicon. XRD pattern also exhibited some very small peaks which may be due to impurities remained after HCl treatment. SEM photograph of the product was given in Figure 4.14. The EDX result also confirmed that the product was silicon (Figure 4.15). The oxygen peak seen in EDX result was thought to be the result of the oxidation of silicon surface during washing and cleaning processes.
Figure 4.10: XRD pattern of (a) reduced pellet after 8 hours of electrolysis and HCl treatment (b) SiO$_2$ (ICDD no: 46-1045) and (c) Si (ICDD no: 27-1402).

Figure 4.11: XRD pattern of (a) reduced pellet after 16 hours of electrolysis, before HCl treatment (b) CaCO$_3$ (ICDD no: 5-0586) and (c) Si (ICDD no: 27-1402).
Figure 4.12: SEM image of the reduced pellet for 16 hours at 2.8 V. Legends 1 and 2 shows CaCO₃ and Si, respectively.

Figure 4.13: XRD pattern of reduced pellet after 16 hours of electrolysis and HCl treatment.
Figure 4.14: SEM photograph of the sample produced by 16 hours of electrolysis and HCl treatment.

Figure 4.15: EDX analysis result of the sample produced by 16 hours of electrolysis and HCl treatment.
In order to determine the impurity level of the silicon due to contaminations from the cathode contacting materials and other components of the cell, elemental analysis was conducted. For this purpose inductively coupled plasma-mass spectrometer (Perkin Elmer DRC II model ICP-MS) was used. The levels of important impurities; Fe, Ni and Cr are given in Table 1. Contamination by Fe was thought to be due to the stainless steel plates that were used to sandwich the Kanthal wire meshed pellet. Ni and Cr contaminations could be resulted from the stainless steel plates and Kanthal wire mesh.

Table 4.1: ICP-MS results of Si powder

<table>
<thead>
<tr>
<th>Element</th>
<th>Concentration</th>
</tr>
</thead>
<tbody>
<tr>
<td>Fe (%)</td>
<td>0.449±0.005</td>
</tr>
<tr>
<td>Cr (%)</td>
<td>0.218±0.005</td>
</tr>
<tr>
<td>Ni (μg/g)</td>
<td>64.10±1.86</td>
</tr>
</tbody>
</table>

The color of the silicon powder obtained, after HCl treatment of electrochemically reduced samples was, unexpectedly, a tone of brown which is different from the gray color of bulk silicon. Brownish color was also observed from the photographs of the reduced products of some other studies [33, 35]. Pistorius and Fray [37] reported a similar color, brick-red, in their study. However, the color of the silicon was reported as grey in the study of Jin et.al. [38]. Pistorius and Fray [37] claimed that the brick-red color of the silicon may be due to an interference effect of silicon and calcium silicate mixture with very fine powder size. However, absence of calcium silicate in the products of the present study does not support this hypothesis. Silicon powders with brown color due to nanometer-scale crystallite size were reported in other studies [47, 48]. In the light of these reports calculation of crystallite size was performed by using Maud program [49]. The output of the program in terms of phase determination is given in Figure 4.16. As it can be seen from small differences in intensities of peaks shown in the lower part of this figure,
silicon phase was identified clearly after refinement calculations of the program. Weighted R-value, \( R_w \), for this refinement was 12.97 % and lattice parameter, \( a \), for this cubic structure was calculated as 5.433 Å which was nearly the same as the lattice parameter for the matching card, 5.431 Å. According to this calculation, crystallite size of the silicon produced in the present study was below 50 nm. Therefore, different tones of red and brownish color may be the result of the nanometer-scale crystallite size of the silicon powder.

![XRD spectrum](image.png)

**Figure 4.16:** The output of the Maud program [49] showing the phase identification of XRD results obtained from Si powder after 16 hours of electrolysis.

### 4.1.4 Effects of Temperature and Particle Size of Starting Material

To investigate the effect of temperature, \( \text{CaCl}_2 \) (70 mole%)–\( \text{NaCl} \) (30 mole%) salt mixture was used as electrolyte for the first time in this work. The experiments were conducted at 750°C, 800°C and 850°C at 2.8 V. According to current versus time and
total charge versus time graphs given in Figure 4.1 and Figure 4.2 temperature increase has a positive effect in increasing the reduction rate. This increase was thought to be due to increase in diffusion of O\textsuperscript{2−} ions with increasing temperature. This result is consistent with the reported rate determining step of the electrodeoxidation process of SiO\textsubscript{2} [35], which is the diffusion of O\textsuperscript{2−} ions at the cathode.

In order to test the effect of particle size of the starting material, SiO\textsubscript{2} pellets having particle size smaller than 64 μm and smaller than 38μm were prepared. According to graphs given in Figure 4.1 and Figure 4.2, reduction rate slightly increased with decreasing particle size of the starting material from sub-64 μm to sub-38 μm at 750°C. This is in accord with the expectations, because smaller particle size yields condensed pellets that decrease the diffusion and the conduction paths.

### 4.2 Electrolysis of Bulk SiO\textsubscript{2} Plate

In the study of Yasuda et. al. [39] reduction rate of bulk SiO\textsubscript{2} was reported to be faster than that of porous SiO\textsubscript{2} pellet. However, a systematic comparison of electrodeoxidation of porous pellet and bulk plate forms of SiO\textsubscript{2} was not available. Bulk SiO\textsubscript{2} plate (20x20x1 mm) was wrapped by Kanthal wire (Ø: 0.15 mm) mesh and sandwiched between stainless steel plates to form the cathode as in the case of porous SiO\textsubscript{2} pellets. Electrolysis experiments were performed by applying 2.8 V at 750°C in molten CaCl\textsubscript{2}-NaCl salt mixture. An electrochemical reduction experiment was performed for 5 hours by using bulk SiO\textsubscript{2} plate. In order to compare the reduction rates of porous SiO\textsubscript{2} pellets and bulk SiO\textsubscript{2} plate, current versus time curves for each one under the same conditions are given in Figure 4.17. Only the initial 10 hours of the curve for the pellet is repeated from Figure 4.3. The total charges that passed through the cell during electrochemical reduction as a function of time are given in Figure 4.18. It is apparent from this figure that, bulk silica plate was reduced faster than the porous pellet, similar to the report given by Yasuda et.
Figure 4.17: Comparison of current versus time curves during the electrolysis of bulk SiO$_2$ plate and porous SiO$_2$ pellet at 2.8 V for 5 hours.

Figure 4.18: Total charge versus time graphs during the electrolysis of porous SiO$_2$ pellet and bulk SiO$_2$ plate.
al. [39]. The slower reduction rate of the porous SiO$_2$ pellet was explained with reference to surface roughness compared with that of plate. Because reduction follows the rough contour on pellets, but it proceeds along a straight line on the flat surface of the dense SiO$_2$ plate [39].

XRD analysis after the HCl treatment of the product confirmed that the product consisted of mainly silicon and unreduced amorphous SiO$_2$ (see Figure 4.19). The amorphous structure of unreduced SiO$_2$ still remains, showing typical pattern of intensities.

![XRD pattern of the bulk SiO$_2$ plate after 5 hours of electrolysis and HCl treatment.](image)

**Figure 4.19:** XRD pattern of the bulk SiO$_2$ plate after 5 hours of electrolysis and HCl treatment.
4.3 Cyclic Voltammetry Studies

Cyclic voltammetry technique is used to gain knowledge about the mechanism of the electrochemical reactions. Usually three electrodes are used in the cyclic voltammetry studies: working electrode, counter electrode and reference electrode. Working electrode is usually the electrode of which mechanism is desired to be known. In this technique electrode potential ramps linearly as a function of time. This ramp is called as scan rate. When a specified potential range is covered then the potential is reversed to complete the cycle in this technique. In a three-electrode cyclic voltammetry study, current is passed between the working electrode and the counter electrode, but potential is measured between the working electrode and the reference electrode. When an electrode reaction (oxidation or reduction) takes place, the slope of the voltage versus current graph (voltammograms) changes (either in positive or in negative direction). By this way electrode potentials can be measured without overpotentials and IR drops.

The cyclic voltammetry was performed, between porous SiO$_2$ pellet cathode (working electrode) and the tungsten reference, to determine the potential at which cathode reaction:

$$\text{SiO}_2 + 4\text{e}^- = \text{Si} + 2\text{O}^{2-}$$  \hspace{1cm} (12)

begins, continues and ceases down with increasing or decreasing applied voltage. The graphite anode was the counter electrode in this study. The cyclic voltammetry was performed over the range 0 to 1.5 V, with 2 mV/s scan rate. According to CV (current versus voltage) curve given in Figure 4.20, slope of the curve started to increase at about 0.24 V, and then formed a peak at about 0.7 V. Further increase in electrode potential caused polarization of the electrode and resulted in decrease in current passing through the cell and slowed down the electrode reaction. The midpoint of the onset and the peak values of the current, found as 0.47 V (see Figure 4.20), corresponds to the potential for the cathode reaction [50].
Figure 4.20: Cyclic voltammogram of the porous SiO₂ pellet. Scan rate: 20 mV/s; scan range: 0-1.5 V.

The determination of only the cathode potential does not give conclusive information about cell potential. The cyclic voltammetry is also used between two electrodes of a cell. In this case, unlike three-electrode arrangement, the applied potential between the anode and the cathode is changed along the cycle. From the changes in the slopes of voltage versus current diagrams, the currents and the voltages corresponding to the commencement and the cease of cell reactions can be determined.

In the case of cyclic voltammetry between porous silica cathode and graphite anode, without using the reference electrode, the cycle covered the range 0 to 3.5 V with 2 mV/s scan rate. The experiments were again performed at 750°C in molten CaCl₂-NaCl salt mixture. The cyclic voltammogram of this study is given in Figure 4.21. The cell reaction was not observed until about 1.70 V. At this point, slope of the CV curve started to increase and then the reduction peak was recorded at about 2.90 V. If the potential corresponding to midpoint of the onset and the peak values of the
current was taken as the cell potential, it was found as 2.3 V (see Figure 4.21). Therefore the potential applied in the present study, 2.8 V, was appropriate for the reduction of SiO$_2$.

![Cyclic voltammetry result between porous SiO$_2$ pellet cathode and graphite rod anode. Scan rate: 20 mV/s; scan range: 0-3.5 V.](image)

Figure 4.21: Cyclic voltammetry result between porous SiO$_2$ pellet cathode and graphite rod anode. Scan rate: 20 mV/s; scan range: 0-3.5 V.

Applied potential to the cell, $E_{app}$, was distributed over: the overall cell reaction, $E_{reaction}$, voltage drop due to resistances of electrolyte, $E_{electrolyte}$, and electrical connections, $E_{electrical connections}$, and the overvoltages, $\eta$. Then:

$$E_{app} = E_{reaction} + E_{electrolyte} + E_{electrical connections} + \eta$$  \hspace{1cm} (13)

Overall reaction for the reduction of SiO$_2$ to silicon in the present study is given as:

$$\text{SiO}_2(s) + C(s) = \text{Si}(s) + \text{CO}_2(g)$$  \hspace{1cm} (14)
Gaseous product was considered as CO$_2$ rather than CO as in the case of aluminum electrolysis [51]. The standard Gibbs energy change of this reaction at 1050K is 325504 J [2]. The standard potential of this reaction can be calculated by using the formula:

$$E^\circ = -\frac{\Delta G^\circ}{nF}$$  \hspace{1cm} (15)

where $E^\circ$ is the standard potential of the cell reaction in V, when standard Gibbs energy change, $\Delta G^\circ$ is taken in J, n, number of Faradays of charge that has to pass through the cell for above reaction, as 4, and F, Faraday’s constant, as 96487 coulombs/gr.equivalent. The reversible potential for the overall reaction is calculated as -0.84 V. Therefore, $E_{\text{reaction}}$ in applied potential given in above equation is 0.84 V when all the components of above reaction are in their standard states.

Electrical conductivity of CaCl$_2$ (75.5 mole%)-NaCl (24.5 mole %) salt mixture at 750°C is calculated as 1.75 ohm$^{-1}$.cm$^{-1}$ by using 1.56 and 1.95 ohm$^{-1}$.cm$^{-1}$ conductivities at 700°C and 800°C [52] respectively. Therefore, resistance, $R$, of the electrolyte is calculated from the formula:

$$R = \rho \frac{l}{A}$$  \hspace{1cm} (16)

By using 0.57 ohm.cm resistivity, $\rho$, 1.5 cm inter electrode distance, l, and 1.77 cm$^2$ surface area of the cathode, A; the resistance of the electrolyte was found as 0.48 ohm. The ohmic voltage of the electrolyte, $E_{\text{electrolyte}}$ was calculated as 0.58 V when 1.19 A current, corresponding to 2.30 V applied cell potential for SiO$_2$ reduction in present cyclic voltammetry study.

The resistances along the electrical connections were calculated by using the resistivity of stainless steel ($1.2\times10^{-6}$ ohm.m) [53] and resistance of 3.5 mm Kanthal wire (0.12 ohm/m) [54] found in the literature. The total resistance along the stainless steel and Kanthal wires were calculated as 0.15 ohm at 750°C from equation (14). Therefore voltage drop along the electrical connections was found as
0.18 V. Small additional voltage drop along graphite rod and copper connection wires were not included in above value.

CO$_2$ overvoltage on graphite anode can be calculated by using Tafel plots:

$$\eta = a + b \log i$$  \hspace{1cm} (17)

where $\eta$ is the overvoltage, $a$ and $b$ are Tafel coefficients, and $i$ is the current density. Tafel coefficients for anodic overvoltage in cryolite melts [51] are given in Table 4.2.

<table>
<thead>
<tr>
<th>Temperature (°C)</th>
<th>Tafel Range (A.cm$^{-2}$)</th>
<th>a(V)</th>
<th>b(V)</th>
</tr>
</thead>
<tbody>
<tr>
<td>790</td>
<td>0.01 – 1</td>
<td>0.60</td>
<td>0.22</td>
</tr>
</tbody>
</table>

Assuming similar overvoltages for CO$_2$ formation at 750°C in molten salt electrolyte used in this study, the anodic overvoltage was calculated as 0.59 V for the present study. Summation of all contributions yields about 2.19 V as the total applied voltage. Although small voltage drop along graphite rod and copper connection wires were not included in the computations and overvoltage computations was based on above assumption, only 0.11 V difference between experimental (2.30 V) and calculated (2.19 V) cell voltages support the proposed cell reaction.
CHAPTER 5

CONCLUSIONS

Electrodeoxidation of porous SiO$_2$ pellets and a bulk SiO$_2$ plate were investigated in molten CaCl$_2$ salt and/or CaCl$_2$-NaCl salt mixture. Electrochemical reduction experiments for porous SiO$_2$ pellets were performed by applying 2.8 V potential difference at 850°C when pure CaCl$_2$ used, and at 850°C, 800°C and 750°C when CaCl$_2$-NaCl salt mixture used as electrolytes. The experiment for the bulk SiO$_2$ plate was conducted in CaCl$_2$-NaCl salt mixture at 750°C by applying 2.8 V potential.

Electrochemical reduction of porous SiO$_2$ pellets and bulk SiO$_2$ plate to silicon was successfully achieved. However, spectroscopic analysis revealed that the produced silicon was contaminated by the nickel and stainless steel plates which were used as the cathode contacting materials and does not meet the required specifications of SOG-Si. Impurity level of silicon may be reduced to the desired range for SOG-Si by advancement of the materials for the cell components.

The effect of temperature on the electrochemical reduction of porous SiO$_2$ pellets was studied by using CaCl$_2$-NaCl salt mixture as the electrolyte for the first time. A slight increase in the reduction rate could be attained with either increasing temperature from 750°C to 850°C or decreasing the SiO$_2$ particle size from sub-64 μm to sub-38 μm. Besides, employment of the Kanthal wire mesh to porous SiO$_2$ pellet when placing it into the cathode assembly increased the reduction rate. It was also observed that addition of NaCl to the electrolyte decreased the reduction rate.

Contrary to the study of Jin and his coworkers [38], complete reduction of porous SiO$_2$ pellets with similar geometry and dimensions under the same applied DC
potential, could not be achieved in 4 hours at 850°C in CaCl₂ molten salt electrolyte. Complete reduction of porous SiO₂ pellets at 750°C in CaCl₂-NaCl was achieved after 16 hours of electrolysis in the present study.

The color of the produced silicon powder was a tone of brown. This color may be the result of nanometer-scale crystallite size of the silicon powder.

Cyclic voltammetry studies showed that the overall reduction potential of porous SiO₂ pellet was 2.30 V at 750°C in molten CaCl₂-NaCl salt mixture when the current was 1.19 amperes. The potential of the cathode half cell reaction for the reduction of porous SiO₂ pellet was found as 0.47 V relative to tungsten reference electrode under the same conditions.

Reduction rate was found to be faster when bulk SiO₂ plate was used instead of porous SiO₂ pellet as the cathode material.
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